

**AMENDMENTS TO THE CLAIMS:**

The following listing of claims replaces all prior listings, and all prior versions, of claims in the application.

**LISTING OF CLAIMS:**

1. – 10. (Cancelled).

11. (New) A manufacturing method of a semiconductor integrated circuit device, comprising:

(a) storing apparatus log data that are data outputted from semiconductor manufacturing apparatus that processes a semiconductor wafer, contain a plurality of headers and show a state of the semiconductor manufacturing apparatus in an apparatus log data memory;

(b) detecting whether there are abnormal data in the apparatus log data stored in the apparatus log data memory or not at an abnormal data detector; and

(c) outputting a result detected at the abnormal data detector to a result output portion,

wherein the process (b) includes lower rank processes below:

(b1) acquiring a search key assigning the header of the apparatus log data;

(b2) extracting past data coinciding with the apparatus log data in a content of the header assigned with the acquired search key from a past data memory;

(b3) calculating a standard deviation from the extracted past data; and

(b4) detecting based on the calculated standard deviation whether the abnormal data are present in the apparatus log data or not,

wherein, of assignment of the header with the search key, an assignment of an apparatus name is grouped to enable to apply on a group base.